

Cover photograph

Lifetime Achievement Award to Professor Hiroo Kinoshita

The cover photograph shows the Medal of the Lifetime Achievement Award to Professor Hiroo Kinoshita, director of the Center for EUV Lithography at Lasti. Central five patterns of 12" Si wafer was made by EUV Lithography. Professor Kinoshita was awarded the prize as inventor of the reduced projection exposure by extreme ultraviolet lithography.

In 2010, Professor Kinoshita was awarded the 10th Yamazaki-Teiichi Prize for pioneer of the EUV Lithography and continuous contribution to industrialization, and was awarded the Medal of Science in Hyogo Prefecture for his world first proposal using the extreme ultraviolet light lithography technology in semiconductor processing, and contributed to the practical application to develop innovative technology.



LASTI Annual Report 2010 **Vol.12(2010)**

2012.3 Published by

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